

AMENDMENTS TO THE CLAIMS

Claims 1-4 (Cancelled)

5. (Currently Amended) The wafer-shipping device as claimed in ~~claim 4~~, claim 6, wherein the pressure inside the shipping box approximates atmospheric pressure.

6. (Currently Amended) ~~The wafer-shipping device as claimed in claim 4~~, A wafer-shipping device, comprising:

a shipping box for a wafer, the shipping box having at least one through hole;

a packaging bag to contain the shipping box; and

a dry inert gas filling the packaging bag and the shipping box, surrounding the wafer;

wherein the dry inert gas is nitrogen.

7. (Currently Amended) The wafer-shipping device as claimed in ~~claim 4~~, claim 6, wherein after pumping an air out of the shipping box and the packaging bag, the dry inert gas fills the shipping box and the packaging bag.

Claim 8 (Cancelled)

9. (Currently Amended) The wafer preserver as claimed in ~~claim 8~~, claim 10, wherein the pressure inside the container approximates atmospheric pressure.

10. (Currently Amended) ~~The wafer preserver as claimed in claim 8;~~ A wafer preserver, comprising:
a container having at least a vacant space;
a wrapping for packaging the container; and
a gas filling the container and surrounding the wafer;
wherein the gas is dry nitrogen.

11. (Currently Amended) The wafer preserver as claimed in ~~claim 8,~~ claim 10, wherein after pumping an air from the container and the wrapping, the gas fills the container and the wrapping.

Claim 12 (Cancelled)

13. (Currently Amended) The semiconductor preserver as claimed in ~~claim 12,~~ claim 14, wherein the pressure inside the first space approximates atmospheric pressure.

14. (Currently Amended) ~~The semiconductor preserver as claimed in claim 12;~~ A semiconductor preserver, comprising:
a first space for containing the semiconductor;
a second space is formed by a gas-proof material surrounding the first space;
a vacant space between the first space and second space; and

an inert gas filling the first space, the second space and the vacant space, wherein the insert

inert gas is dry nitrogen.

15. (Currently Amended) The semiconductor preserver as claimed in ~~claim 12~~, claim 14, wherein after pumping an air out of the first space, the second space and the vacant space, the inert gas fills the first space, the second space and the vacant space.